

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)	MAIL STOP RCE
)	
Shigeyuki Akimoto et al.)	Group Art Unit: 2624
)	
Application No.: 10/556,916)	Examiner: Vanchy Jr., Michael J.
)	
Filed: November 15, 2005)	Confirmation No.: 1621
)	
For: OUTER SURFACE-INSPECTING)	
METHOD, MASTER PATTERNS)	
USED THEREFOR, AND OUTER)	
SURFACE-INSPECTING)	
APPARATUS EQUIPPED WITH)	
SUCH A MASTER PATTERN)	

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated July 24, 2008, please amend the
above-identified patent application as follows: